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(21)Application number : 51-104864 (71)Applicant : HITACHI LTD
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(54) ELECTRON MICROSCOPE PROVIDED WITH SAMPLE IRRADIATING ELECTRON BEAM QUANTITY MEASURING UNIT

(57)Abstract:

PURPOSE: To protect a sample from being damaged by irradiating electron beam by using a means—which measures and observes a sample irradiating electron beam quantity at a sample observation time—and a means—which controls an irradiating electron beam quantity within the range where the sample cannot be damaged.

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